

First principle investigation of hydrogen passivation for selective atomic layer deposition of Pt, Cu, and Au metals

Giorgia Barile, Federico Ravera, Yuri Ardesi, Fabrizio Mo, Gianluca Piccinini, and Mariagrazia Graziano

May 7, 2025

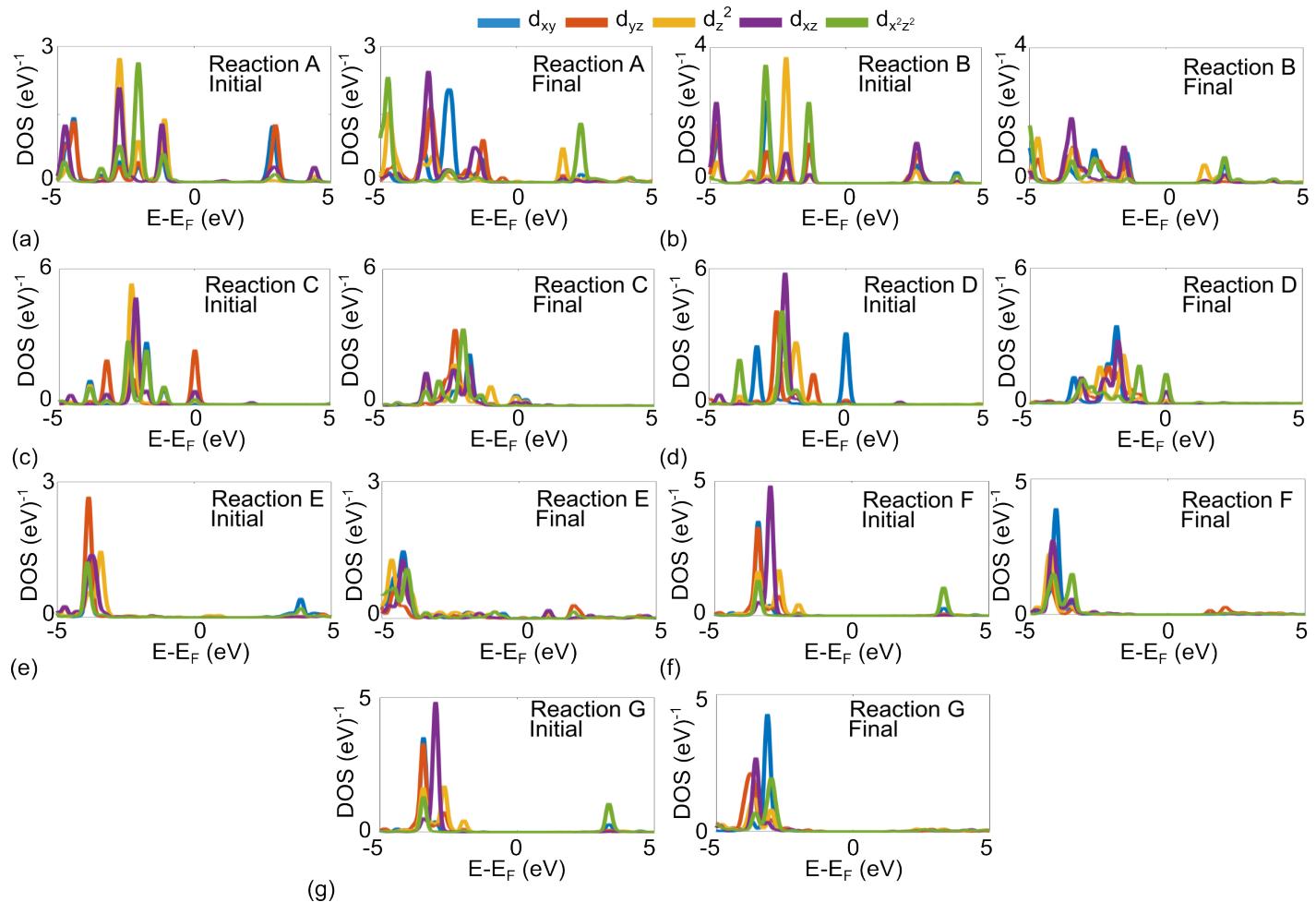


Figure 1: Projected density of states (PDOS) onto the d orbitals of the metal atom in the precursor for Reactions A–G, shown in panels (a)–(g), respectively. In each panel, the left side shows the PDOS before and after interaction with the Si(100) or H–Si(100) substrate. Comparisons highlight changes in d-orbital features upon adsorption, providing insight into the degree of hybridization and the nature of the precursor–surface interaction.

Table 1: Table reporting the values for Entropy, enthalpy and Gibbs Free energy, for all the temperatures analyzed for all Metals (Pt, Cu, Au).

	T°	S	T°S ORCA [Kcal/mol]	H ORCA [Kcal/mol]			$\Delta G = \Delta H - \Delta TS$	ΔG
				Final Step	Initial Step	H Initial Step		
<i>Me₃AuPM₃ 273.15K</i>	A	79.2548	79.6121	-5751457.3753	-5751402.7568	-0.3573	-54.6184	-54.2612
	B	82.9830	80.8537	-5754505.0068	-5754470.0232	2.1293	-34.9837	-37.1130
<i>Me₃AuPM₃ 298.15K</i>	A	92.0604	92.6192	-5751451.5633	-5751396.9630	-0.5588	-54.6002	-54.0415
	B	96.5712	93.0116	-5754498.7154	-5754464.4226	3.5596	-34.2928	-37.8523
<i>Me₃AuPM₃ 373.15K</i>	A	134.8598	135.5590	-5751432.4826	-5751377.6734	-0.6992	-54.8092	-54.1100
	B	142.0898	139.2755	-5754477.9863	-5754443.1551	2.8143	-34.8312	-37.6454
<i>Cu(acac)₂ 273.15K</i>	A	84.6556	83.7551	-6917712.8076	-6917673.1583	0.9004	-39.6493	-40.5498
	B	87.7405	84.9564	-6920747.8167	-6920748.3795	2.7841	0.5628	-2.2213
<i>Cu(acac)₂ 298.15K</i>	C	98.2586	97.2185	-6917706.6380	-6917667.0735	1.0401	-39.5645	-40.6046
	D	102.0247	98.9597	-6920741.2368	-6920741.8644	3.0650	0.6275	-2.4375
<i>Cu(acac)₂ 373.15K</i>	E	143.5451	142.0592	-6917686.4562	-6917647.1316	1.4858	-39.3246	-40.8105
	F	149.83548	145.9284	-6920719.5186	-6920720.3624	3.9264	0.8438	-3.0826
<i>Me₃AuPM₃ 273.15K</i>	E	76.4219	67.9210	-5904842.3398	-5904748.7964	8.5008	-93.5434	-102.0443
	F	84.9613	82.1515	-5907973.6293	-5907944.5383	2.8099	-29.0910	-31.9008
<i>Me₃AuPM₃ 298.15K</i>	G	83.2554	82.1518	-5907928.9793	-5907944.5389	1.1036	15.5596	14.4559
	H	88.8272	79.3346	-5904836.7043	-5904743.5392	9.4926	-93.1651	-102.6577
<i>Me₃AuPM₃ 373.15K</i>	F	98.8271	95.7714	-5907967.2512	-5907938.2038	3.0557	-29.0474	-32.1031
	G	97.0407	95.7793	-5907922.6133	-5907938.2395	1.2614	15.6262	14.3649
<i>Me₃AuPM₃ 373.15K</i>	E	130.3238	117.6907	-5904818.2347	-5904726.1651	12.6331	-92.0697	-104.7028
	F	145.1636	141.4363	-5907946.3200	-5907917.3424	3.7273	-28.9776	-32.7049
<i>Me₃AuPM₃ 373.15K</i>	G	143.0824	141.4366	-5907901.6007	-5907917.3429	1.6458	15.7423	14.0965

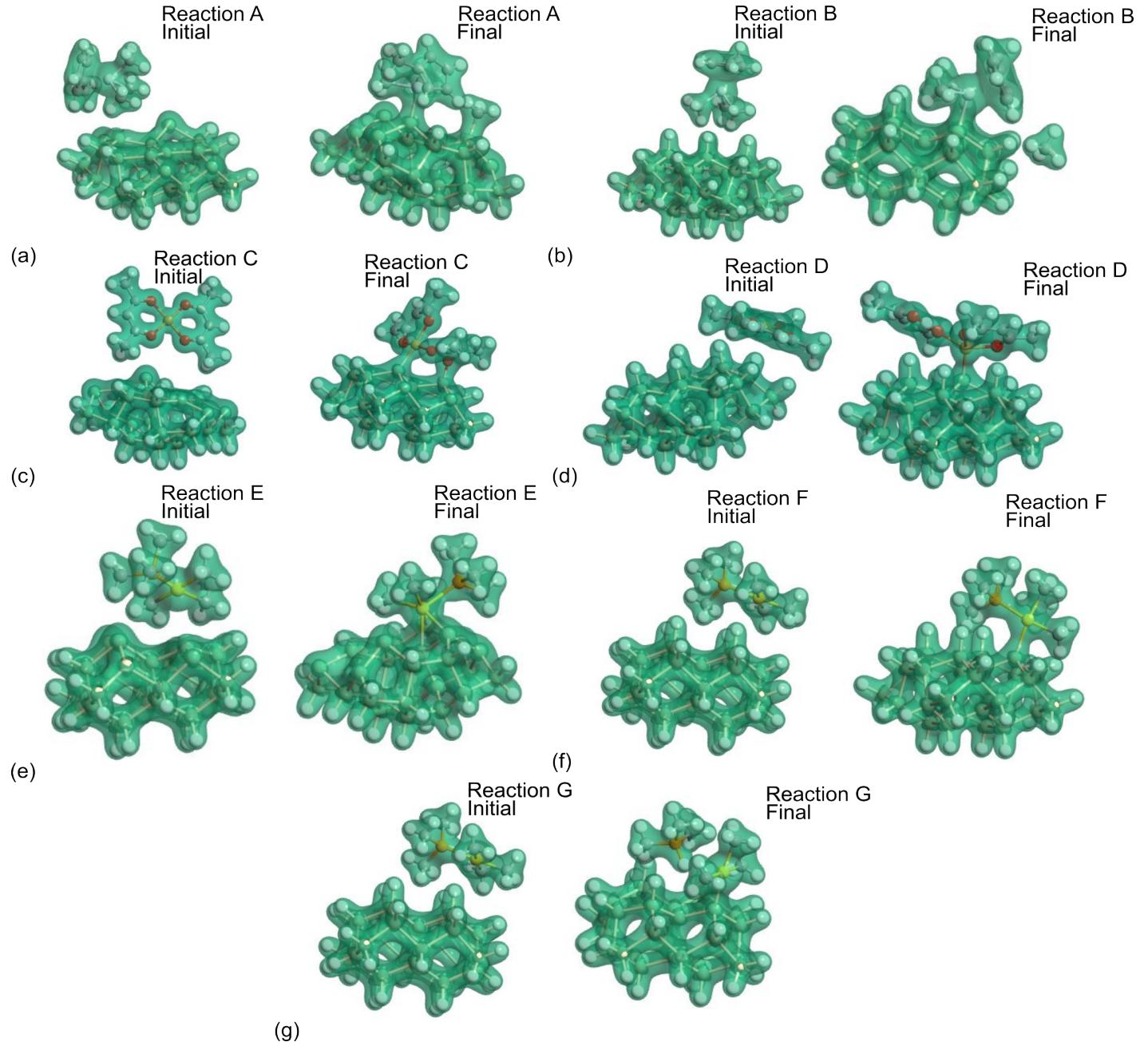


Figure 2: Electron density plots for Reactions A–G, shown in panels (a)–(g), respectively. Each panel illustrates the charge redistribution upon adsorption of the precursor on the Si(100) or H-Si(100) surface. In all cases, an isovalue equal to 0.3 \AA^{-3} is considered.

Reaction		Initial state [e]	Final state [e]
A	Precursor	0.0120428303708	0.105269448315
	Substrate	-0.0120428303706	-0.105269448238
B	Precursor	0.00544528489243	0.0131105298932
	Substrate	-0.00544528489161	-0.0131105298925
C	Precursor	0.040967419284	0.117565432675
	Substrate	-0.0409674192548	-0.117565432772
D	Precursor	0.0481875713274	0.103194763725
	Substrate	-0.0598857011368	-0.111322277312
E	Precursor	-0.0546376581764	0.146259559312
	Substrate	0.0546376581763	-0.146259559272
F	Precursor	0.0291139828143	0.116546227398
	Substrate	-0.0291139828145	-0.116546227398
G	Precursor	0.0291139828143	0.193717811962
	Substrate	-0.0291139828145	-0.193717811963

Table 2: Electronic charge (in units of e) transferred during the initial and final states for each reaction, distinguishing between precursor and substrate contributions.